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I am pleased to submeto the "Modification of Micro	nit our prop odensitomet	osed Stateme ter Digital Re	nt of Work I eadout System	pertaining	
Our fixed price proper formance period of 65 days. times during the program arout of the modifications will	We will no	eed access to pate that inst	mplates a to the machine allation and	3 2 or 3	STA
I trust this meets all questions, please contact me	of your req	quirements.	If you have	any	
		Sino	erely,		•
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March 27, 1969

Declass Review by NIMA/DOD

Approved For Release 2003/12/19: CIA-RDP78B05171A000800080012-1

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STATEMENT OF WORK

MODIFICATION OF MICRODENSITOMETER : DIGITAL READOUT SYSTEM

INTRODUCTION

This stateme	t of work describes a proposed program to modify the	
	Model 985 Microdensitometer Readout System. Two modifica-	, <u></u>
tions are involved.	The first will permit shorter and more accurate scan lengths that	an
can presently be of	ained. The second will permit a sampling rate of ten samples pe	Эľ
micron.		

MODIFICATION OF SCAN LENGTH

Presently the minimum length of scan is limited by the physical size of the microswitches used to set the ends of the scan. We propose to use the coordinate counter to establish scan length. This should also provide a more accurate scan since the switch variations will be eliminated.

One end of the scan will be the zero coordinate. This requires that the operator move the carriage to the desired starting point and reset the appropriate coordinate counter at that point. The desired length of scan will then be set decimally in microns on six thumbwheel switches. Reversal of scan direction will occur when the coordinate counter reaches zero and when it reaches the set value.

To accomplish this will require the addition of six decimal switches, six decade counters and associated interfacing.

This modification will be usable on either the X or Y axis scans. The present SCAN AXIS switch will make this selection.

INCREASED SAMPLING RATE

The present maximum sampling rate is one sample per micron. The purpose of this modification is to increase this rate to ten samples per micron. It should be noted that the present digital system has a maximum sample rate expressed in samples per

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Approved For Release 2003/12/19: CIA-RDP78B05171A000800080012-1 second. Increasing the number of samples per micron will then reduce the maximum scan rate. In three color operation, the maximum scan rate will be five millimeters per minute.

To accomplish this, we propose to provide a crystal controlled oscillator and divide the frequency down appropriately to give ten samples per micron. Since the stage is driven by a synchronous motor, the rate of travel is constant except during start and stop. On the assumption that the 60 eps power source is very nearly constant in frequency, the crystal controlled oscillator will then provide an essentially constant distance between samples. Our experience indicates that the 60 eps frequency is sufficiently stable. However some testing of this either before or after the modification should be performed. If instability of the power source should be a problem, power for the scan motors can be derived from the crystal oscillator. However, our present program does not include this.

Basically, this modification will consist of adding a crystal controlled oscillator and a frequency divider. The present equipment will then be changed as necessary. A switch will be provided to permit either the added sample signal generator to be used or to permit operation in the present manner. Also, a multiple position switch will be added so that a ten samples per micron signal can be obtained at all scan rates.

PROGRAM

It will be necessary for one man to visit the equipment early in the program in order to determine space available, necessary package configuration, etc. He may also find it desirable to make some electrical checks but primarily this visit is necessary for packaging reasons.

Modifications will then be designed	and fabricated at		
Installation will be performed by a		engineer.	Complete check-
out will follow installation.			

SCHEDULE

Modification units will be complete and ready for installation within sixty (60) days after the program is initiated. Installation and check-out will require one week.

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	「ALOG FORM ase 2003/12/19 : CIA-RDP78B05171/	0008000800121969			
Microdensitometer Modifica- tions (Scan Control and Sampling System)	This project is to develop a and a time based sampling sys	stem for the 1032T			
3. CONTRACTOR NAME	4. LOCATION OF CONTRA				
	L				
5. CLASS OF CONTRACTOR Manufacturer	6. TYPE OF CONTRACT FP				
7. FUNDS	8. REQUISITION NO.	9. BUDGET PROJECT NO.			
FY 19 68 \$ None					
FY 19 69	10. EFFECTIVE CONTRACT DATE (Begin - end)	AA - Confidential			
FY 19 70 \$ None	May 1969 - July 1969	T - Unclassified W - Unclassified			
12. RESPONSIBLE DIRECTORATE/OFFICE/PRO	1				
DDI/NPIC/TSSG/DED/					
(a) scan microscopic areas of	1032T Microdensitometer is lim imagery without producing ext acceeds 170 lines per millimeter	raneous data and (b)			
14. TYPE OF WORK TO BE DONE					
Engineering Development					
15. CATEGORIES OF EFFORT					
MAJOR CATEGORY	SUB-CATEGORIES				
	Microdensitometry				
Precision Measurement	Optical Systems				
Contractor will modify the Mi with digital switches and cou density sampling system from sampling rate of 10 samples processing or related contracts (A This contract will be run con	currently with a contract to m re is no overlap on these proje	l the length of the scan, and (b) change the se which will allow a ent rate of 1 sample per micrometer).			
and comparison logic will rep to be preset to from 1 microm scan length will eliminate th reduce costly processing of t it will be triggered by a cry the stage movement. The osci and will permit more frequent	e extraneous data now produced he data. The sampling system we stal oscillator (the "clock") is llator will allow better controps sampling, thereby reducing the sampling of the sampling thereby reducing the sampling the sampli	ade counters, switches to allow the scan length cise programming of the on small scans and will ill be modified so that instead of directly by of the sampling rate			
19. APPROVED BY AND DATE OFFICE DEPUTY DIR		resortation imagery.			
	ase 2003/12/19 : CIA-RDP78B05171/	\000800080012-1			
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GROUP I Excluded from automatic downgrading and